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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re the Application of: **Tomoharu NAKANO et al.**

Group Art Unit: **Not yet assigned**

Application Number: **10/552,606**

Examiner: **Note yet assigned**

Filed: **October 5, 2005**

Confirmation Number: **6380**

For: **POLISHING LIQUID FOR CMP PROCESS AND POLISHING  
METHOD**

Attorney Docket Number: **052463**

Customer Number: **38834**

**PRELIMINARY AMENDMENT**

Commissioner for Patents  
P. O. Box 1450  
Alexandria, VA 22313-1450

September 29, 2006

Sir:

Prior to the examination of this application, please amend the above-referenced application as follows:

**Amendments to the Claims** begin on page 2 of this paper.

**Remarks** begin on page 7 of this paper.